

# Multivariate Analysis for Main Quality Variable Control in Industry 4.0

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**Keywords:** Multivariate Analysis, Quality Control, Industry 4.0, out-of-Control, Out-of-Quality.

**Abstract:** The  $T^2$  Hotelling one-dimensional control chart representation points out the out-of-control samples but does not display how the secondary variables affects the primary ones considered the main quality variable. From the same depart, the CHI squared distribution, a 2nd degree equation is derived highlighting the main quality variable and its dependence on the secondary ones. This approach allows the identification of out-of-control points that affects quality and require some adjustment of the secondary variables and the out-of-quality points, which need an investigation of the root causes that lead to this undesirable output.

## 1 INTRODUCTION

With the technological innovations made possible by the resources of Industry 4.0, quality control techniques for production processes can and should be refined to keep pace with these changes. Engineers and manufacturing process supervisors can benefit, for example, from clearer and more interactive assessments of sample data generated in manufacturing production (Godina and Matias, 2019). These issues have been presented either as a requirement for the sustainable performance of the industry (Foidl and Felderer, 2016) and to leverage predictive actions resulting from a more instrumentalized quality control—see, for example, (Lee et al., 2019).


Indeed, in several industries, semiconductor, metallurgy, cosmetics etc. there are one or more main quality variables that quantify the product quality (piston ring diameter, solution purity etc.) that are affected by secondary ones that should be investigated when the quality goal is not reached (Palaci-Lopez et al., 2020). These goals can be achieved with stable and well-controlled processes. In this sense, increased quality is defined as a reduction in the variability of processes and products, which can


make of statistical methods essential in efforts to improve processes (May and Spanos, 2006).


As each stage of the manufacturing process has a set of variables whose measurements and control involve a defined number of observations, statistical models are used to monitor deviations of these parameters and thus exercise forms of control to detect process variability and its impact on the product quality. In practice, many factors can influence such a variability as improperly adjusted or controlled machines, operator errors, different operators crew, defective raw material, temperature variation etc. that contribute to increase this variability and increase the production of non-conforming items.

The way these variables are measured is shifting with the Industry 4.0 with the possibility to record 100% of measured data by means of IoT sensors and wireless network (Godina and Matias, 2019). This huge amount of data must be classified to consider the many factors that can influence the variability as pointed previously.

Therefore, in the context of Industry 4.0 it is necessary the simultaneous statistical control of two or more quality characteristics making possible to

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control the impact of variability. In this context, multivariate control charts (MCC) are used in the aggregated monitoring of two or more process or product variables. The  $p$ -dimensional points (that is, the values of  $p$  random variables or statistics of interest derived from them) are represented one-dimensionally and presented in graphs similar to Shewhart charts, simplifying the task of simultaneous control of variables.

The paper is structured as follows: In Section 2, the motivation for this approach is presented, highlighting how multivariate analysis can bring new information for process monitoring and control, and how to specify control limits based on capability index. Section 3 presents the ellipse control expressions for multivariate analysis. Section 4 is dedicated to the  $T^2$  Hotelling approach. Finally, in the Section 5, the method proposed is applied to three variables highlighting the concept of out-of-control and out-of-quality points.

## 2 WHY MULTIVARIATE ANALYSIS? THE MOTIVATION

Industry 4.0 will allow at low cost a significant spread of sensor technology on shop floors gathering a huge volume of data. New levels of quality control have been demanded to match the current abundance of data and the facilities made possible by new automation and data intelligence technologies, in a way to extract more effective value from this new production management potential—see, for example, (Moyne and Iskandar, 2017), (Lee et al., 2019).

The resources of statistical process control, which have been applied for a long time in the productive environment, are also gaining state-of-the-art studies and becoming more specialized to further contribute to the quality management (Zhong et al., 2017), (Tu et al., 2009), (Sindhumol et al., 2018). Some approaches include cutting-edge technological solutions, for example neural network in a system to detect and classify fabric defects (Mahmud et al., 2021), which even though not within the scope of statistical control, illustrates the efforts applied to improve quality control practices in view of the news demands of the Industry 4.0.

When it comes to the production of semiconductors—such as solid-state drive (SSD) and multi-chip packages, to name a few types—, which can involve multistage and multistep processes, many factors can influence the quality of the production process in an aggregated and interdependent way. Several techniques have been used to analyze the multiple variables acting in this process, with

approaches that try to capture the process particularities, monitor the control limits established for production and deepen the analyses to increase the interpretability of the collected data.

By focusing on a timeline of the technical literature of this century, one can observe that two decades ago, (Skinner et al., 2002) already compared multivariate statistical methods to analyze wafer data. A few years later, based on multivariate analysis, (Ma et al., 2010) extracted key variables from a broad set of variables measured with small number of runs. Currently, amidst the challenges of big data in semiconductor production, (Saib et al., 2021) presents a multivariate analysis method for large amounts of multidimensional data. Already (Chien and Chen, 2021) developed a collinear multivariate model-based approach to extend managerial capabilities in intelligent semiconductor manufacturing.

In this context, there is an issue that quality management may have multivariate quality control tools to detect the variations among data that are not independent. In other words, data should be jointly considered, otherwise the quality management analysis can lead to erroneous conclusions. Another issue is how to show the way secondary variables affects primary ones.

This second point is the motivation of this paper. We propose to consider a practical example to highlight the proposition.

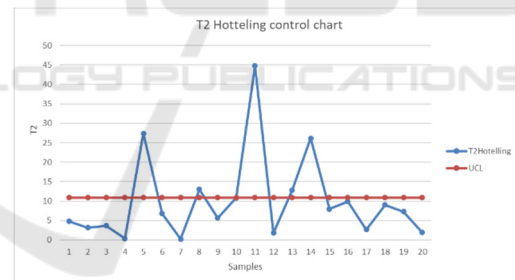


Figure 1: T2 Hotelling control chart.

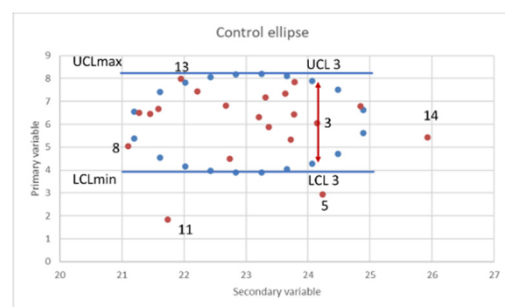


Figure 2: X-Y Control ellipse. Sample 3 control limits.

Figure 1 shows the  $T^2$  Hotelling control chart analyzing two variables. Figure 2 displays the X-Y

dispersion of the variables and the ellipse multivariate control chart.

The samples 5, 11 and 14 are out-of-control points but a difference can be pointed. The value of the secondary variable of sample 14 is within the maximum control limits of the primary variable and can be adjusted to be inside the ellipse to ensure primary variable control. Differently, the same does not happen with the value of the secondary variable of samples 5 and 11 that are out of the maximum control limits of the primary variable directly affecting the quality.

The ellipse control chart is not easily visualized when several secondary variables are considered, since is difficult to construct the ellipse for more than two quality variables. It is proposed a X-Y control chart, as illustrated in Figures 3 (a) and (b) for two variables. The UCL, Upper Control Limit and LCL, Lower Control Limit are the intersection of the vertical straight-line of each sample with the ellipse curve, changing with the time sequence of the samples. The break of the UCL and LCL limits at samples 8 and 14 is explained by the lack of solution because they not vertically intersect the ellipse.

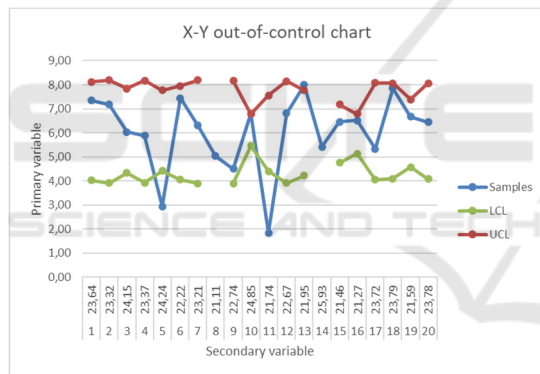


Figure 3(a): X-Y Out-of-control chart.

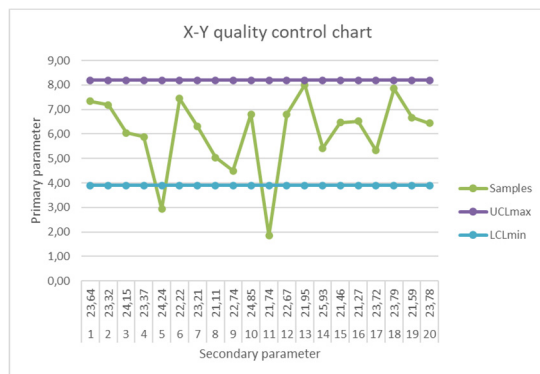


Figure 3(b): X-Y quality control chart.

The X-Y quality control chart points out the samples that are not inside the quality range

delimited by UCLmax and LCLmin, which respectively represent the maximum of the UCL values and the minimum of the LCL values shown in figure 3(a)

For more than two secondary variables, the set will be displayed by a table.

In the following sections the ideas herein presented are developed.

### 3 ELLIPSE CONTROL CHART

Equation (1) is the matrix exponent of the multivariate normal density function.

$$(\bar{X} - \bar{\bar{X}})^T S^{-1} (\bar{X} - \bar{\bar{X}}) \quad (1)$$

where:

$\bar{X} = (\bar{X}_1, \bar{X}_2, \dots, \bar{X}_p)$  is the mean vector of the  $p$  variables,

$\bar{\bar{X}}$  = the mean vector of means

and  $S$  the matrix of covariances.

Suppose that  $p$  quality variables are jointly distributed according to the bivariate normal distribution with sample averages of the quality variables computed from a sample of size  $n$ , then the statistics

$$\chi_{\alpha,p}^2 = n(\bar{X} - \bar{\bar{X}})^T S^{-1} (\bar{X} - \bar{\bar{X}}) \quad (2)$$

will have a chi-square distribution with  $p$  degrees of freedom.

Let  $\chi_{\alpha,p}^2$  be the upper  $\alpha$  percentage point of the chi-square distribution with  $p$  degrees of freedom

For  $p=2$  the following equations holds:

$$\chi_{\alpha,2}^2 = n \left( \frac{1}{\sigma_1^2 \sigma_2^2 - \sigma_{12}^2} \right) (\sigma_2^2 v_1^2 + \sigma_1^2 v_2^2 - 2v_1 v_2 \sigma_{12}) \quad (3)$$

$$v_i = \bar{X}_i - \bar{\bar{X}}_i$$

$\sigma_i^2$  variance of  $i$ ,  $\sigma_{ij}$  covariance between  $i, j$

Equation (3) is the base of the ellipse control example of Figure 2 taking variable 1 as primary and 2 as secondary for a given  $n$  and  $\alpha$ .

For  $p$  variables, taking  $p = 1$  as the primary one, the equation (2) can be expressed as:

$$\chi_{\alpha,p}^2 = n[v_1 \quad V_{1,p-1}] \begin{bmatrix} \sigma_1^2 & S_{1,p-1} \\ S_{p-1,1} & S_{p-1,p-1} \end{bmatrix}^{-1} \begin{bmatrix} v_1 \\ V_{p-1,1} \end{bmatrix} \quad (4)$$

$V_{i,j}, S_{i,j}$  subarray of  $i$  lines and  $j$  columns

Expression (4) is a 2<sup>nd</sup> degree equation for variable 1.

## 4 THE MULTIVARIATE APPROACH

Generally, MCC (Multivariate Chart Control) are used in situations where there is a significant correlation between the variables to be monitored, since in most of the multivariate processes the variables interfere and suffer interference with each other, thus having a strong correlation. In addition, these charts are useful in cases where the variables are not correlated, as they are capable of monitoring processes in which there is a possibility of false alarms when the operator finds problems in a certain variable that is not necessarily interfering with the process. According to (Montgomery, 2013), the difference between univariate and multivariate control is the increase in the complexity and levels of automation of production processes, together with the collaboration of growing computational support.

For (Mason and Young, 2001), a control procedure based on Hotelling's  $T^2$  statistics observes the fact that a change in a variable can cause a ripple effect throughout a system. By considering the interrelationships between variables, the  $T^2$  statistics produces a powerful tool that is useful in detecting subtle changes in the system. This fact explains the expansion of multivariate control within industries, simultaneously monitoring the various quality characteristics (process variables)—see, for example, the application of (Tavares and Ramos, 2006) in the Brazilian aluminum industry, and (Nunes et al., 2018) discuss the use of this and other multivariate control charts in industrial processes with automatization and large data volumes.

The most popular multivariate control charts are the Chi-squared and Hotelling's  $T^2$  charts. They follow the same line of the univariate Shewhart chart and can detect large variations in the process along with its behavior related to its mean. The Chi-squared control chart considers that the vector of the mean of the characteristics and the covariance matrix of the variables involved are known. We know that in practice this almost does not happen. Thus, in our approach, we considered the Hotelling's  $T^2$  chart, since it uses assumptions that are estimated by means of preliminary samples collected from the process, when it is under statistical control.

Now, we present a summary of the ideas about Hotelling's  $T^2$  charts contained in (Montgomery, 2013), in order to formalize it. The  $T^2$  chart was developed by Hotelling in 1947, which was a pioneer researcher on multivariate control charts. In formal terms, to build the chart, the quadratic form expressed in equation (5) is considered:

$$T^2 = n(\bar{X} - \bar{\bar{X}})^T S^{-1}(\bar{X} - \bar{\bar{X}}) \quad (5)$$

Being more specific, for each line  $k$  of the sample and each characteristic  $j$ , it is considered that

$$\bar{X}_{ij} = \frac{1}{n} \sum_{i=1}^n X_{ijk} \quad (6)$$

$$s_{jk}^2 = \frac{1}{n-1} \sum_{i=1}^n (X_{ijk} - \bar{X}_{ij})^2 \quad (7)$$

In both equations, (6) and (7),  $j = 1, 2, \dots, p$  and  $k = 1, 2, \dots, m$ . While the covariance between features  $j$  and  $h$  at the  $k$ -th coordinate is given by equation (8)

$$s_{jhk} = \frac{1}{n-1} \sum_{i=1}^n (X_{ijk} - \bar{X}_{jk})(X_{ihk} - \bar{X}_{hk}) \quad (8)$$

with  $k = 1, 2, \dots, m$  and  $j \neq h$ . Consequently,  $\bar{\bar{X}}$  and  $S$  are obtained considering the averages

$$\bar{\bar{X}}_j = \frac{1}{m} \sum_{k=1}^m \bar{X}_{ij}, \quad j = 1, 2, \dots, p \quad (9)$$

$$\bar{s}_j^2 = \frac{1}{m} \sum_{k=1}^m s_{jk}^2, \quad j = 1, 2, \dots, p$$

$$\bar{s}_{ij} = \frac{1}{m} \sum_{k=1}^m s_{jhk}, \quad j \neq h$$

and the matrix.

$$S = \begin{pmatrix} \bar{s}_1^2 & \dots & \bar{s}_{1p} \\ \vdots & \ddots & \vdots \\ \bar{s}_{p1} & \dots & \bar{s}_p^2 \end{pmatrix} \quad (10)$$

It is important to note that, in this case,  $\bar{\bar{X}}_j$  represents the elements of vector  $\bar{\bar{X}}$  e  $S$  represents the covariance matrix considering the mean of the covariance of each line of the sample.

The construction of Hotelling's  $T^2$  chart has two distinct phases. Phase I consists of using the graph to test whether the process was under control when the first observations were extracted. In this case, the objective is to obtain a set of data under control for establishing the control limits. Phase II, in turn, uses these limits to test whether the process remains under control, when future observations are extracted.

Upon completion of the Phase I, the limits are defined as expressed in equations (11) and (12)

$$UCL I = \frac{p(m-1)(n-1)}{mn-m-p+1} F_{\alpha, p, mn-m-p+1} \quad (11)$$

$$LCL I = 0 \quad (12)$$

where  $p$  is the number of characteristics being considered simultaneously,  $n$  is the size of the subgroup,  $m$  is the total of samples and

$F_{\alpha,p,mn-m-p+1}$  is a point of a portion of the upper percentage of the  $F$  distribution with  $p$  and  $mn - m - p + 1$  degrees of freedom. For the case in which future observations are extracted from the process, in Phase II, the control limits are calculated via equations (13) and (14)

$$UCL II = \frac{p(m+1)(n-1)}{mn-m-p+1} F_{\alpha,p,mn-m-p+1} \quad (13)$$

$$LCL II = 0 \quad (14)$$

where  $p$ ,  $m$  and  $n$  represent the same parameters defined previously. When a large number of samples is considered, it is customary to use  $UCL = \chi_{\alpha,p}^2$  as the upper control limit in both phases I and II. In this case,  $\chi_{\alpha,p}^2$  represents the upper percentage point of the Chi-squared distribution with  $p$  degrees of freedom—see (Montgomery, 2013) for more details.

### 5 APPLICATIONS

A hypothetical example is considered to exemplify the proposed multivariate analysis.

Table 1: Samples.

Sample	$\bar{X}_1$	$\bar{X}_2$	$\bar{X}_3$
1	23.64	7.34	5.18
2	23.32	7.18	3.78
3	24.15	6.04	5.32
4	23.37	5.88	4.72
5	24.24	2.94	4.50
6	22.22	7.44	4.24
7	23.21	6.30	6.44
8	21.11	5.04	5.22
9	22.74	4.50	4.66
10	24.85	6.80	6.04
11	21.74	1.85	5.36
12	22.67	6.81	5.06
13	21.95	8.00	3.32
14	25.93	5.42	3.78
15	21.46	6.46	3.40
16	21.27	6.51	5.20
17	23.72	5.33	5.38
18	23.79	7.85	7.46
19	21.59	6.66	5.32
20	23.78	6.44	4.46
$\bar{\bar{X}}$	23.03	6.04	4.94

Table 1 shows the mean of the variables considering  $n = 5, m = 20$  and  $p = 3$ . Primary variable  $I$  is dependent of the other two secondary variables.

The  $T^2$  Hotelling chart points out eight out-of-control points as shown in figure 3.

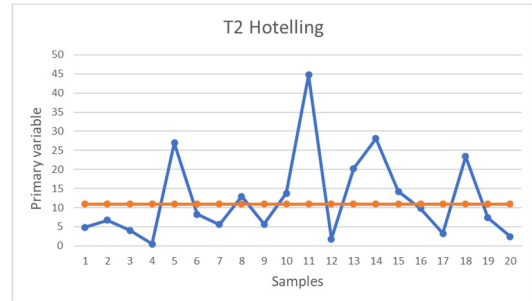


Figure 4:  $T^2$  Hotelling chart.

The X-Y chart based on equation (4) highlights the out-of-controls points but also those that directly affects the primary variable which measure the output quality. The control limits UCL and LCL shown in Figure 5 are time-varying with the sample sequence, since they represent the intersection of the vertical straight-line of each sample with the ellipse curve, as explained in Section 2. In Figure 6, the X-Y quality control chart points out the samples that are not inside the quality range delimited by UCLmax and LCLmin, which respectively represent the maximum of the UCL values and the minimum of the LCL values shown in figure 5

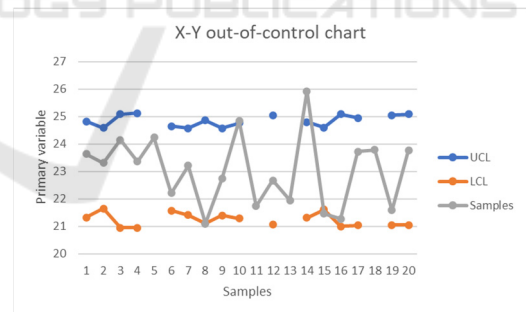


Figure 5: Out-of-control chart.

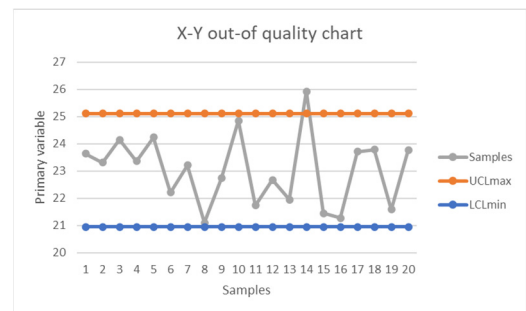


Figure 6: Quality control chart.

The control limits UCL/LCL enclose the out-of-control points and UCLmax/LCLmin delimit the quality control area, concerning the primary variables whose limits are determined by the secondary ones. Sample 14 can be considered an out-of-quality point and Table 1 displays the values of the secondary variables which lead to this nonconformity. In other words, the out-of-control points need a correct setting of the secondary variables, but the out-of-quality points need an investigation of the root causes that lead to this output.

## 6 CONCLUSIONS

In many applications concerning quality control in Industry 4.0 there are sensors that measure the output quality variables and those that measure the secondary variables affecting the output quality. A quality control analysis should take this particularity into account.

Due to correlation between measured variables in the industrial process Multivariate analysis is of paramount importance because individual variable control can lead to erroneous conclusions.

Multivariate analysis based on the  $T^2$  Hotelling is a one-dimensional control chart representation pointing out the out-of-control samples but does not display how the secondary variables affects the primary ones, considered the main quality variables.

Based on the Chi-squared distribution, a 2<sup>nd</sup> degree equation is derived highlighting the main quality variable and its dependence on the secondary ones. This approach allows the identification of out-of-control points that affects quality and require some adjustment of the secondary variables and the out-of-quality points, which need an investigation of the root causes that lead to this undesirable output.

For further work, we planned to include data assimilation into the statistical modelling and consider predictive uncertainty quantification in this approach, with the purpose of evaluating to what extension this analytical detailing will contribute to support more assertive decisions. Such an evaluation might be feasible, as long as we have a significant increase in the amount of monitored data.

## ACKNOWLEDGEMENTS

The authors would like to thank the Brazilian Ministry of Science, Technology and Innovations for the financial support part of this project through the PADIS (Program of Support for the Technological

Development of the Semiconductor and Displays Industry).

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